



#QB
JEWIA
3-21-02
500.37149X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: S. MAEDA et al.
Serial No.: 09/294,137
Filed: April 20, 1999
For: DEFECT INSPECTION METHOD AND APPARATUS
Art Unit: 2621
Examiner: B. Werner

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MAR 20 2002

Technology Center 2600

AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

March 11, 2002

Sir:

In response to the Office Action of October 11, 2001,
please amend the above-identified application as follows.

Submitted herewith is a credit card payment form in
payment of the additional claim fee of \$72.00 due in
connection with the filing of the present amendment.

IN THE CLAIMS

Cancel claims 3 and 16 without prejudice or disclaimer of
the subject matter thereof.

Amend claims 1-2, 4-15, and 17-30 as follows:

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D1
R1
--1. (Amended) A method of inspecting patterns, comprising
the steps of:

picking up a first pattern formed on a substrate to
produce a first image;